

FORM PTO-1449 (SUBSTITUTE) U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE INFORMATION DISCLOSURE STATEMENT BY APPLICANT (37 CFR 1.98(b))	Attorney Docket No.: L&L-10078 Applicant Alfred Kersch et al. Filing Date August 24, 2001	Applic. No. 09/939,330
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U.S. PATENT DOCUMENTS

EXAMINER INITIALS		PATENT NO.	DATE	PATENTEE	CLASS	SUB CLASS	FILING DATE
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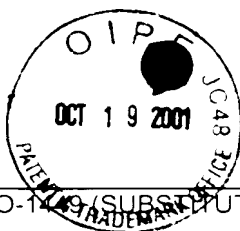
		DOCUMENT NO.	DATE	COUNTRY	CLASS	SUB CLASS	TRANSL. YES NO
EF	J	03 197 394 A	08/28/91	Japan			X
EF	K	04 137 532 A	05/12/92	Japan			X
	L						
	M						
	N						

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)

EF	O	J.L. Archer et al.: "Chemical Vapor Deposition Of Single-Crystal Metal Oxides. II. Encapsulation Of Polycrystalline Conductors In Single-Crystal Ferrite", J. Phys. Chem. Solids, Suppl. 1967, No. 1, pp. 337-340
EF	P	Jing Zhao et al.: "Low Pressure Organometallic Chemical Vapor Deposition Of High -T _C Superconducting YBa ₂ Cu ₃ O _{7-δ} Films", Solid State Communications, Vol. 69, No. 2, 1989, pp. 187-189

EXAMINER 	DATE CONSIDERED 12/14/02
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EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.



FORM PTO-1749 (SUBSTITUTE)

U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICEINFORMATION DISCLOSURE
STATEMENT BY APPLICANT
(37 CFR 1.98(b))Attorney Docket No.:
L&L-10078Applic. No.
09/939,330

Applicant

Alfred Kersch et al.

Filing Date
August 24, 2001

Group Art Unit

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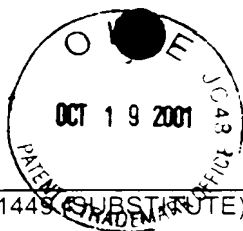
EF	O	Shogo Matsubara et al.: "Preparation of epitaxial ABO_3 perovskite-type oxide thin films on a (100) $\text{MgAl}_2\text{O}_4/\text{Si}$ substrate", J. Appl. Phys. Vol. 66, No. 12, December 15, 1989, pp. 5826-5832
EF	P	Clive D. Chandler et al.: "Chemical Aspects of Solution Routes to Perovskite-Phase Mixed-Metal Oxides from Metal-Organic Precursors", Chem. Rev. 1993, No. 93, pp. 1205-1241

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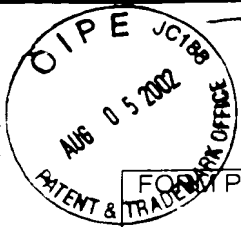
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EF	O	D. Saulys et al.: "An examination of the surface decomposition chemistry of lithium niobate precursors under high vacuum conditions", Journal of Crystal Growth, No. 217, 2000, pp. 287-301
EF	P	Y. Gao et al.: "Effects of precursors and substrate materials on microstructure, dielectric properties, and step coverage of (Ba,Sr)TiO ₃ films grown by metalorganic vapor deposition", Journal of Applied Physics, Vol. 87, No. 1, January 1, 2000, pp. 124-132

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U.S. PATENT DOCUMENTS


EXAMINER INITIALS		PATENT NO.	DATE	PATENTEE	CLASS	SUB CLASS	FILING DATE
EF	A	5,399,387	03/21/95	Law et al.			
EF	B	5,508,067	04/16/96	Sato et al.			
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EF	J	0 296 891 A2	12/28/88	Europe			X
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